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Substitute for form 1449/PTO

**INFORMATION DISCLOSURE
STATEMENT BY APPLICANT**

(Use as many sheets as necessary)

Complete if Known

Application Number	Unknown
Filing Date	Herewith
First Named Inventor	Collins
Art Unit	Unknown
Examiner Name	Unknown
Attorney Docket Number	000894 USA C02/ISM/H

Sheet 1 of 4

U. S. PATENT DOCUMENTS

Examiner Initials*	Cite No. ¹	Document Number	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number-Kind Code ² (if known)			
RD		US- 4384918	05/24/1983	Abe	
RD		US- 4412133	10/25/1983	Eckes et al.	
RD		US- 4480284	10/30/1984	Tojo et al.	
RD		US- 4645218	02/24/1987	Ooshio et al.	
RD		US- 4665463	05/12/1987	Ward et al.	
RD		US- 4832781	05/23/1989	Mears	
RD		US- 5055964	10/08/1991	Logan et al.	
RD		US- 5104834	04/14/1992	Watanabe et al.	
RD		US- 5117121	05/26/1992	Watanabe et al.	
RD		US- 5151845	09/29/1992	Watanabe et al.	
RD		US- 5166856	11/24/1992	Liporace et al.	
RD		US- 5258047	11/02/1993	Tonsikue et al.	
RD		US- 5275683	01/04/1994	Arami et al.	
RD		US- 5280156	01/18/1994	Niori et al.	
RD		US- 5315473	05/24/1994	Collins et al.	
RD		US- 5324053	06/28/1994	Kubota et al.	
RD		US- 5325261	06/28/1994	Horwitz	
RD		US- 5350479	09/27/1994	Collins et al.	
RD		US- 5382469	01/17/1995	Kubota et al.	

FOREIGN PATENT DOCUMENTS

Examiner Initials*	Cite No. ¹	Foreign Patent Document	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages Or Relevant Figures Appear	T ⁶
		Country Code ³ -Number ⁴ -Kind Code ⁵ (if known)				
RD		JP-227748	01/30/1990			✓
RD		JP-4367247	12/18/1992			✓
RD		EP-439000-B1	09/14/1994			✓
RD		EP-635869-A1	04/22/1994			✓
RD		JP-6232243	08/19/1994			✓
RD		EP-791956-A	08/27/1996			✓

Examiner
Signature

/Robert Dang/

Date
Considered

05/02/2006

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Sheet **2** of **4****U. S. PATENT DOCUMENTS**

Examiner Initials*	Cite No. ¹	Document Number	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number-Kind Code ² (if known)			
RD		US- 5463526	10/31/1995	Mundt	
RD		US- 5542559	08/06/1996	Kawakami et al.	
RD		US- 5720818	02/24/1998	Donde et al.	
RD		US- 5886863	03/23/1999	Nagasaki et al.	
RD		US- 5792562	08/11/1998	Collins et al.	
RD		US- 5684669	11/4/1997	Collins et al.	
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		Country Code ³ "Number" ⁴ "Kind Code" ⁵ (if known)				
RD		JP-9017850	01/17/1997			✓

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05/02/2006

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		Art Unit	Unknown
		Examiner Name	Unknown
Sheet 3 of 4	Attorney Docket Number		000894USAC02/ISM/HDP

NON PATENT LITERATURE DOCUMENTS			
Examiner Initials*	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²
RD		Daviet, et al. "Electrostatic Clamping Applied to Semiconductor Plasma Process-I. Theoretical Modeling," J. Electrochem. Soc. 140(11):3245-3255 (November 1993)	
RD		Daviet, et al. "Electrostatic Clamping Applied to Semiconductor Plasma Processing-II. Experimental Results," J. Electrochem. Soc., 140(11):3256-3261 (November 1993)	
RD		Nakasuji, et al. "Low Voltage and High Speed Operating Electrostatic Wafer Chuck," J. Vac. Sci. Technol. A., 10(6):3573-3578 (November/December 1992)	
RD		Watanabe, et al., "Effect of Additives on the Electrostatic Force of Alumina Electrostatic Chucks," J. of the Ceramic Soc. of Jpn., 100(1):1-6 (1992)	
RD		Watanabe, et al. "Electrostatic Force and Absorption Current of Alumina Electrostatic Chuck," Jp. J. Appl. Phys., 32(Pt.1, No.2):864-871 (1993)	
RD		Watanabe, et al. "Electrostatic Force and Absorption Current of Alumina Electrostatic Chuck," Jpn. J. Appl. Phys. 31(Pat.1, No.7):2145-2150 (1992)	
RD		Watanabe, et al., "Resistivity and Microstructure of Alumina Ceramics Add with TiO2 Fired in Reducing Atmosphere," J. of the Ceramic So. of Jpn Int Ed, 101:1076-1083	
RD		Wright, et al., "Low Temperature Etch Chuck: Modeling and Experimental Results of Heat Transfer and Wafer Temperature," J. Vac. Sci. Tech. A 10(4):1065-1070 (July/August 1992)	

Examiner Signature	/Robert Dang/	Date Considered	05/02/2006
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U.S. PENDING PATENT APPLICATIONS
 ATTORNEY DOCKET NO.: 000894 USA C02/ISM/HDP/CVD/JCW
 S/N: N/A - FILED: HERewith
INVENTORS: COLLINS, ET AL.

EXAMINER INITIAL		PENDING U.S. PATENT APPLICATIONS
RD	D1	U.S. Patent Application entitled, "Surface Preparation to Enhance the Adhesion of a Dielectric Layer"; filed April 26, 1996; Serial No. 08/639,156; Inventor: Arik Donde; Attorney Docket No. 1245
	D2	
	D3	
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